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The microstructure and properties of a buried AIN layer produced by nitrogen implantation into pure aluminum (Thin Solid Films, Volume: 289, Issue: 1-2)

Lu, H.L.; Sommer, W.F.; Borden, M.J.; Tesmer, J.R.; Wu, X.D., pp. 17-21,
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Tunnel barrier growth dynamics of Nb/AlO<sub>x</sub>-Al/Nb and Nb/AlN<sub>x</sub>-Al/Nb Josephson junctions (Physica - C - Superconductivity, Volume: 241, Issue: 1/2)

Neuhaus, M.; Jutzi, W.; Dolata, R., pp. 25-29, <u>Article Full-text PDF (363 KB)</u>
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Monte carlo simulation of electron transport in wurtzite aluminum nitride (Solid State Communications, Volume: 105, Issue: 10)

Bhapkar, U.V.; Foutz, B.E.; Eastman, L.F.; O'Leary, S.K.; Shur, M.S., pp. 621-626, Article Full-text PDF (578 KB)
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Impurity Study of Alumina and Aluminum Nitride Ceramics: Microelectronics Packaging Applications (Applied Radiation and Isotopes, Volume: 48, Issue: 1)

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• Sproul, W.D., pp. 1-7, Article Full-text PDF (812 KB)
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Low temperature nitridation of transition metals with hydrazine (Thin Solid Films, Volume: 256, Issue: 1/2)

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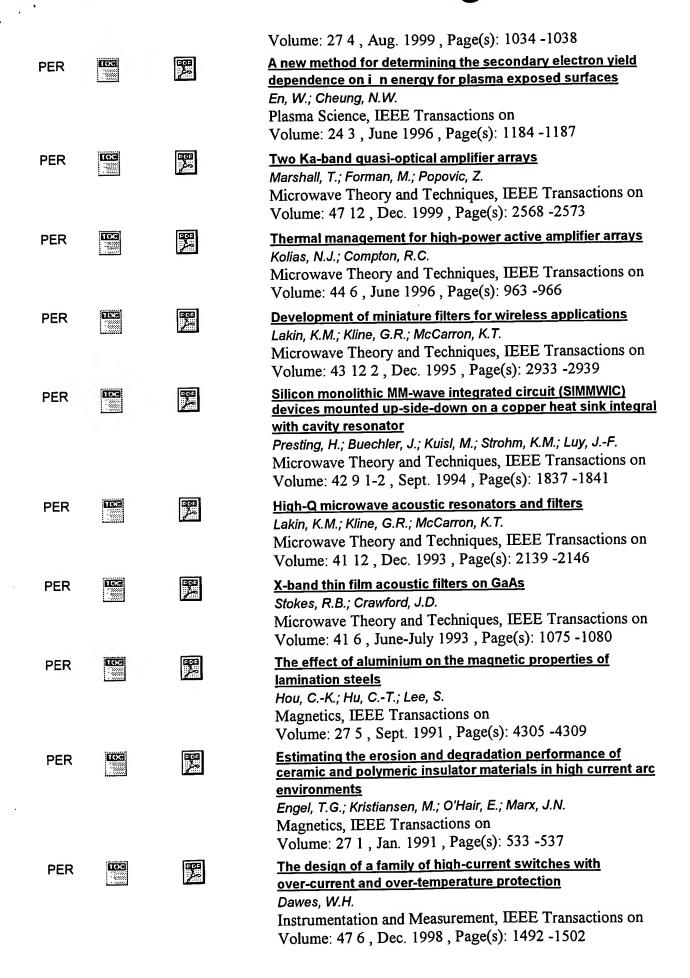
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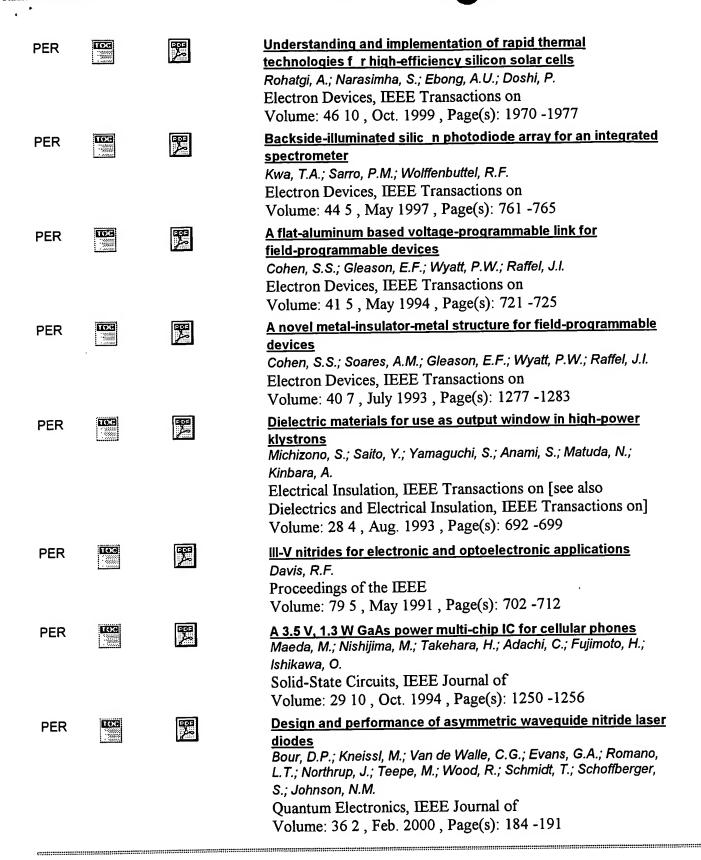
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			Components, Hybrids, and Manufacturing Technology, IEEE Transactions on [see also IEEE Trans. on Components, Packaging, and Manufacturing Technology, Part A, B, C] Volume: 13 2, June 1990, Page(s): 313 -319
PER		<b>E</b>	Aq-Pd thick film conductor for AlN ceramics  Kurihara, Y.; Takahashi, S.; Yamada, K.; Endoh, T.  Components, Hybrids, and Manufacturing Technology, IEEE  Transactions on [see also IEEE Trans. on Components, Packaging, and Manufacturing Technology, Part A, B, C]  Volume: 13 2, June 1990, Page(s): 306-312
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